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**AMENDMENTS TO THE CLAIMS**

Please cancel claims 5 and 6 without prejudice or disclaimer of the underlying subject matter and amend claims 3 and 4 as set forth below:

3. (CURRENTLY AMENDED) A semiconductor device, comprising:  
a conductive layer pattern formed on a substrate;  
a first inter-layer insulating film which covers said conductive layer pattern and is formed on said substrate;  
a first connection hole formed in a upper layer of said first inter-layer insulating film above said conductive layer pattern;  
a second connection hole which reaches said conductive layer pattern from the bottom portion of said first connection hole and then has a smaller diameter than that of said first connection hole and formed on said first inter-layer insulation film;  
a plug having conductivity and filling internal portions of said first connection hole and said second connection hole;  
a second inter-layer insulating film formed on said first inter-layer insulating film, wherein said second inter-layer insulating film includes up to five layers;  
a third connection hole which reaches said plug and is formed through said second inter-layer insulating film; and  
a conductive portion which is connected to said plug and formed in said third connection hole, wherein said plug and said conductive portion are a storage node contact portion of a dynamic random access memory.

4. (CURRENTLY AMENDED) A semiconductor device, comprising:  
a conductive layer pattern formed on a substrate;  
a first inter-layer insulating film which covers said conductive layer pattern and is formed on said substrate;  
a first connection hole formed in a upper layer of said first inter-layer insulating film above said conductive layer pattern;  
a second connection hole which reaches said conductive layer pattern from the bottom portion of said first connection hole and then has a smaller diameter than that of said first connection hole and formed on said first inter-layer insulation film;  
a plug having conductivity and filling internal portions of said first connection

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hole and said second connection hole, wherein the upper surface of said plug is formed to almost the same height as the surface height of said first inter-layer insulating film;

a second inter-layer insulating film formed on said first inter-layer insulating film, wherein said second inter-layer insulating film includes up to five layers;

a third connection hole which reaches said plug and is formed through said second inter-layer insulating film; and

a conductive contact portion which is connected to said plug and formed in said third connection hole, wherein said plug and said conductive portion are a storage node contact portion of a dynamic random access memory.

5. (CANCELED).

6. (CANCELED).